INFORMATION DISCLOSURE CITATION IN AN APPLICATION					ATTY. DOCKET NO. 57810-074	SEF	SERIAL NO. 10/659 346		
					APPLICANT isao Hasegawa, et al.				
(PTO-1449)					FILING DATE September 11, 2003 GROUP 2813				
U.S. PATENT DOCUMENTS									
EXAMINER'S INITIALS	CITE NO.	Document Number Number-Kind Codes (4 known)		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document		Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear		
		US				<u> </u>			
		US			 		 		
		05			 		 		
		US			 	·			
		US							
		US							
		US							
		US					 		
		US					 		
		US	·						
-		us							
US US									
FOREIGN PATENT DOCUMENTS EXAMINER'S Foreign Patent Document Publication Date Name of Patentee or Pages, Columns, Translation									
INITIALS	CITE NO.	_		MM-DD-YYYY	Applicant of Cited Document	Lines When Relevant Figu Appear	re		
							Yes	No	
LL			JP P2002-93702A	03/29/2002	SANYO ELECTRIC COLTD		(Japan w/English Abstract)		
200		JP P2001-189458A		07/10/2001	SANYO ELECTRIC CO LTD		(Japan w/English Abstract)		
		\models						_	
		├							
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)									
EXAMINER'S INITIALS Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.									
De		"Large Grain Poly-Si TFTs by Scanning CW Laser Crystallization," Hara et al. AM-LCD '02, Digest of Technical Papers, July 10-12, 2002 pp. 227-230							
De		Extended Abstracts (The 48th Spring Meeting, 2001); The Japan Society of Applied Physics and Related Societies. JSAP Catalog Number. AP 011109-02 (03/28/2001) pg. 900							
X		21st Century Version "A Handbook of Applied Forming for Thin Film," April 22, 2003							
EXAMINER DATE CONSIDERED SAMINER DATE CONSIDERED SAMINER DATE CONSIDERED SAMINER DATE CONSIDERED SAMINER DATE CONSIDERED									

*EXAMINER: Initial if reference considered, whether 6Nnot citation is in conformance with MPEP 909. Uraw line through citation is include copy of this form with next communication to applicant.

1 Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached.